



Docket Number: 081468-0307456

PATENT APPLICATION

Client Reference: P-1794.000-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

VADIM YEVGENYEVICH BANINE, et al.

Group Art Unit: 2851

Application No.: 10/747,613

Examiner: Della J. Rutledge

Filed: December 30, 2003

Confirmation No.: 2894

For: LITHOGRAPHIC APPARATUS AND RADIATION SOURCE COMPRISING A DEBRIS-MITIGATION SYSTEM AND METHOD FOR MITIGATING DEBRIS PARTICLES IN A LITHOGRAPHIC APPARATUS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO/SB/08a. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom. Applicants respectfully request the Examiner return an initialed copy of the enclosed Form PTO/SB/08a to Applicants with the next Office communication to indicate that the references have been considered, per MPEP § 609.

This Information Disclosure Statement is being filed with a Request for Continued Examination. No certification or fee under 37 CFR 1.17(p) is required. Please credit or debit Deposit Account 033975 as needed to ensure consideration of the disclosed information.

Respectfully Submitted,

Emily T. Bell  
Registration Number 47418  
Customer Number: 00909

Date: November 7, 2005  
PILLSBURY WINTHROP SHAW PITTMAN LLP  
Telephone: (703) 905-2000  
Facsimile: (703) 905-2500  
P.O. Box 10500  
McLean, VA 22102

